

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re application of

: **ATTN: BOX RCE**

Yoshio YANASE et al.

: **Confirmation No. 6344**

Serial No. 09/856,982

: Docket No. 2001_0615A

Filed May 30, 2001

: Group Art Unit 2877

METHOD FOR INSPECTING
SEMICONDUCTOR WAFER SURFACE

: Examiner Sang H. Nguyen

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

Petition hereby is made for a two month extension of time to respond to the communication of June 3, 2003.

The fee of \$420.00 is

(X) submitted herewith.
() to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.

() Small entity status of this application is established by a Small Entity Status Assertion which
() is enclosed.
() has been previously submitted.

Respectfully submitted,

Yoshio YANASE et al.

11/31/2003 EFLORES 00000048 09050562

0-10:1252

470.00 US

By

Joseph M. Gorski
Registration No. 46,500
Attorney for Applicants

JMG/edg
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
October 30, 2003